



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: James W. Overbeck
Serial No: 10/034,620
Filed: December 27, 2001
For: WIDE FIELD OF VIEW AND HIGH SPEED SCANNING MICROSCOPY

Examiner: T.Q. Nguyen
Art Unit: 2872

COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

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Huang
4-16-03

RESPONSE

In response to the Office Action mailed December 2, 2002, Applicant responds as follows:

In the Claims:

Original claims 1 - ⁶¹~~62~~ were cancelled prior to examination of this application.

Pending claim ⁶²~~63~~ is being amended herein.

New claims ⁶²⁻⁸⁹~~63-89~~ are introduced herewith.

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62. (Amended) A wide field of view scanner, comprising:
a scanning assembly constructed to provide a light excitation beam emitted from a light source in a scanning motion to an examined surface;
an objective lens associated with and displaced by said scanning assembly arranged to provide an optical path from said light source to the examined surface and from the examined surface fluorescent light, excited in response to said excitation beam, to a light detector; said displaced objective lens and said scanning assembly providing said optical path having substantially constant length;
a translation system constructed to produce movement of the examined surface;
and
a data collection control and processing unit arranged to collect data during the scanning motion and process the collected data.